



Electronic Filing System (EFS) Data
Electronic Patent Application Submission
USPTO Use Only

EFS ID: 56108

Application ID: 10672298



Title of Invention:

METHOD AND APPARATUS USING
INTERFEROMETRIC METROLOGY
FOR HIGH ASPECT RATIO
INSPECTION

First Named Inventor: Shiow-Hwei Hwang

Domestic/Foreign Application: Domestic Application

Filing Date: 2004-02-25

Effective Receipt Date: 2004-02-25

Submission Type: Information Disclosure
Statement

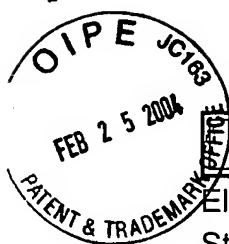
Filing Type:

Confirmation number: 4459

Attorney Docket Number: KLA1P067/P995


Total Fees Authorized:

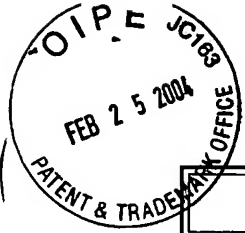
Digital Certificate Holder: cn=Russell Nicholas Swerdon.,ou=Registered Attorneys,ou=Patent and
Trademark Office,ou=Department of Commerce,o=U.S. Government,c=US
Certificate Message Digest: e657524a0566a2027cdc9d06f5e337bbe4d9ba44



TRANSMITTAL

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention	METHOD AND APPARATUS USING INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION									
Application Number: 10/672298 										
Date: 2004-02-25										
First Named Applicant: Shiow-Hwei Hwang										
Confirmation Number: 4459										
Attorney Docket Number: KLA1P067/P995										
<p>I hereby certify that the use of this system is for OFFICIAL correspondence between patent applicants or their representatives and the USPTO. Fraudulent or other use besides the filing of official correspondence by authorized parties is strictly prohibited, and subject to a fine and/or imprisonment under applicable law.</p> <p>I, the undersigned, certify that I have viewed a display of document(s) being electronically submitted to the United States Patent and Trademark Office, using either the USPTO provided style sheet or software, and that this is the document(s) I intend for initiation or further prosecution of a patent application noted in the submission. This document(s) will become part of the official electronic record at the USPTO.</p>										
<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Mr. Russell N. Swerdon Registered Number: 36,943</td><td>RUSSELL N. SWERDON</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Mr. Russell N. Swerdon Registered Number: 36,943	RUSSELL N. SWERDON	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Mr. Russell N. Swerdon Registered Number: 36,943	RUSSELL N. SWERDON	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>KLA1P067-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	KLA1P067-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
us-ids	KLA1P067-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention	METHOD AND APPARATUS USING INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION						
Application Number: 10/672298							
Confirmation Number: 4459							
First Named Applicant: Shiow-Hwei Hwang							
Attorney Docket Number: KLA1P067/P995							
Art Unit: 2621							
Search string: (4818110 or 6262818 or 6078392).pn.							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	4818110	1989-04-04	Davidson		356	358
	2	6262818	2001-07-17	Cuche et al.		359	9
	3	6078392	2000-06-20	Thomas et al.		356	457
Signature							
Examiner Name				Date			